

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of

Hidetoshi OHNUMA, et al

Group: 1756

Serial No. 10/603,689

Examiner: Not Assigned

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Confirmation No. 2872

For: EXPOSURE METHOD, MASK FABRICATION  
METHOD, FABRICATION METHOD  
OF SEMICONDUCTOR DEVICE, AND  
EXPOSURE APPARATUS

**PRELIMINARY AMENDMENT**

MS Non-Fee Amendment  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to the initial examination, please amend the above-identified application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the claims** begin on page 3 of this paper.

**Amendments to the Abstract** begin on page 9 of this paper.

**Remarks/Arguments** begin on page 10 of this paper.